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July 23, 2007

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Art Unit 2851

Commissioner for Patents PO Box 1450 Alexandria, VA 22313-1450

Mail Stop: Amendment

Re: U.S. Utility Patent Application

Application No. 10/677,242; Filed: October 3, 2003

For: Method and Systems for Total Focus Deviation Adjustments on Maskless

Lithography Systems
Inventor: Peter Kochersperger

Our Ref: 1857.2060000

Sir:

Transmitted herewith for appropriate action are the following documents:

- Online Credit Card Payment Authorization in the amount of \$120.00 to cover one (1) month extension of time fee;
- 2. Petition for Extension of Time Under 37 C.F.R. § 1.136(a) Form (PTO/SB/22); and
- Reply Under 37 C.F.R. § 1.111.

The above-listed documents are filed electronically through EFS-Web.

In the event that extensions of time are necessary to prevent abandonment of this patent application, then such extensions of time are hereby petitioned.

Fee payment is provided through online credit card payment. The U.S. Patent and Trademark Office is hereby authorized to charge any fee deficiency, or credit any overpayment, to our Deposit Account No. 19-0036.

Respectfully submitted,

STERNE, KESSLER, GOLDSTEIN & FOX P.L.L.C.

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MKH/srb Enclosures